FISH & RICHARDSON P.C.	U.S. Patent and Trademark Office	PTO/SB/30 (5/2000) use through xx/xx/xxxx. OMB 0651-0031 be: U.S. DEPARTMENT OF COMMERCE								
adjustment provisions of the AIPA. See Changes to Application Ex	Application Number Filing Date First Named Inventor Group Art Unit Examiner Name Attorney Docket Number er 37 C.F.R. §1.114 of the abouted application was filed prior to E.R. §1.53(d) (PTO/SB/29) instead of a samination and Provisional Application	09/134,147 August 14, 1998 Wallace T.Y. Tang 1763 Trung Dang 05542-459003 ve-identified application. May 29, 2000, applicant may wish to RCE to be eligible for the patent term								
consider filing a continued prosecution application (CPA) under 37 C.F.R. §1.53(d) (PTO/SBI/29) instead of a RCE to be eligible for the patent tem adjustment provisions of the AIPA. See Changes to Application Examination and Provisional Application Practice, Interim Rule, 65Fed. Reg 14865 (Mar. 20, 2000), 1233 Off. Gaz. Pat. Office 47 (Apr. 11, 2000), which established RCE practice. 1. Submission required under 37 C.F.R. §1.114 a. Previously submitted i. Consider the amendment(s)/reply under 37 C.F.R. §1.116 previously filed on (Any unentered amendment(s) referred to above will be entered) ii. Consider the arguments in the Appeal Brief or Reply Brief previously filed on iii. Other b. Enclosed i. Amendment/Reply ii. Affidavit(s)/Declaration(s) iii. Information Disclosure Statement (IDS) iv. Other Transmittal of Formal Drawings; (2) Sheets of Formal Drawings 2. Miscellaneous a. Suspension of action on the above-identified application is requested under 37 C.F.R. §1.103(c) for a period of months. (Period of suspension shall not exceed 3 months; fee under 37 C.F.R. §1.17(i) required) b. Other 3. Fee The RCE fee under 37 C.F.R. §1.17(e) is required by 37 C.F.R. §1.114 when the RCE is filed. a. The Director is hereby authorized to charge the following fees, or credit any overpayments, to Deposit Account No. 06-1050 i. RCE fee required under 37 C.F.R. §1.17(e) 12/06/2002 HGEBREH1 00000051 09134147 ii. Extension of time fee (37 C.F.R. §1.16 and 1.17) 01 FC:1801 740.00 GP b. Check in the amount of \$740.00 enclosed c. Payment by credit card (Form PTO-2038 enclosed)										
SIGNATURE OF APPLICANT, AT		· · · · · · · · · · · · · · · · · · ·								
Name (Print/Type) David J. Goren	Registration No. (Attorney/Agen)	n 34 609								

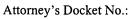
SIGNATURE OF APPLICANT, ATTORNEY OR AGENT REQUIRED								
Name (Print/Type)	David J. Goren	Registration No. (Attorney/Agent)	34,609					
Signature	David G	Date 12/3/02						

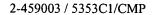
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Wallace Tang

Art Unit : 1763

Serial No.: 09/134,147

Examiner: Trung Dang

Filed

: August 14, 1998

Title

: IN-SITU REAL-TIME MONITORING TECHNIQUE AND APPARATUS FOR

DETECTION OF THIN FILMS DURING CHEMICAL/MECHANICAL

POLISHING PLANARIZATION

Commissioner for Patents Washington, D.C. 20231

PRELIMINARY AMENDMENT

Prior to examination, please amend the application as follows:

In the claims:

Cancel claims 1-10 and 20-31 without prejudice.

- 11. (Amended) A chemical mechanical polisher for planarizing a film on one side of a substrate having two sides comprising at least one light source that transmits light toward the substrate from the side of the substrate with the film to illuminate at least one section on the film and create at least one reflected light signal that is received by at least one device that monitors a dimensional change based on the reflected light signal.
- 12. The polisher as claimed in claim 11 wherein the at least one device is positioned on the same side of the substrate as the light source.
- 13. The polisher as claimed in claim 11 wherein each monitored section is minimized in size to remove signal problems.

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I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, Washington, D.C. 20231.